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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/607,675	06/30/2000	Robert B. Ogle JR.	P1025	1245	
24394	7590 10/02/2002				
LARIVIERE, GRUBMAN & PAYNE, LLP 1 LOWER RAGSDALE, BLDG. 1, SUITE 130 P.O. BOX 3140			EXAMINER		
			NGUYEN, CUONG QUANG		
MONTEREY	, CA 93942	ART UNIT PAPER NUMBER			
			2811	10	
			DATE MAILED: 10/02/2002	2	

Please find below and/or attached an Office communication concerning this application or proceeding.

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j		Application No.	Applicant(s)		
_		09/607,675	OGLE ET AL.	,	
	Office Action Summary	Examiner	Art Unit		
		Cuong Q Nguyen	2811		
Period fo	The MAILING DATE of this communication ap	pears on the cover she two	ith the correspondence addre	ess	
A SH THE - Exte after - If the - If NC - Failt - Any	IORTENED STATUTORY PERIOD FOR REPLIMAILING DATE OF THIS COMMUNICATION. Insions of time may be available under the provisions of 37 CFR 1. If SIX (6) MONTHS from the mailing date of this communication. If period for reply specified above is less than thirty (30) days, a repute to reply within the set or extended period for reply will, by statusting the period for reply within the set or extended period for reply will, by statusting the period for reply will, by statusting the period for reply will. By the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	.136(a). In no event, however, may a libility within the statutory minimum of thin will apply and will expire SIX (6) MON te, cause the application to become Af	reply be timely filed ty (30) days will be considered timely. ITHS from the mailing date of this comn BANDONED (35 U.S.C. § 133).	nunication.	
1)[Responsive to communication(s) filed on	·			
2a)⊠	This action is FINAL. 2b) ☐ T	his action is non-final.			
3)□	Since this application is in condition for allow closed in accordance with the practice unde			merits is	
•	tion of Claims	application			
4)[Claim(s) <u>1-5 and 14-21</u> is/are pending in the				
5.	4a) Of the above claim(s) is/are withdra	awii itofii consideration.			
	Claim(s) is/are allowed.				
•	Claim(s) <u>1-5 and 14-21</u> is/are rejected.				
•	Claim(s) is/are objected to.	/ 1			
,	Claim(s) are subject to restriction and/ tion Papers	or election requirement.			
	The specification is objected to by the Examin	er.	•		
,—	The drawing(s) filed on is/are: a) acc		the Examiner.		
ات (۱۰	Applicant may not request that any objection to t				
11)	The proposed drawing correction filed on				
,—	If approved, corrected drawings are required in r	eply to this Office action.			
12)	The oath or declaration is objected to by the E	xaminer.			
Priority	under 35 U.S.C. §§ 119 and 120				
13)	Acknowledgment is made of a claim for foreign	gn priority under 35 U.S.C.	§ 119(a)-(d) or (f).		
a)				
	1. Certified copies of the priority documer	nts have been received.			
	2. Certified copies of the priority documen	nts have been received in A	Application No		
*	3. Copies of the certified copies of the pri application from the International E See the attached detailed Office action for a lis	Bureau (PCT Rule 17.2(a)).		tage	
14)	Acknowledgment is made of a claim for domes	stic priority under 35 U.S.C	. § 119(e) (to a provisional a	pplication).	
	 a) The translation of the foreign language p Acknowledgment is made of a claim for dome 				
Attachme	•	· •			
	ice of References Cited (PTO-892) ice of Draftsperson's Patent Drawing Review (PTO-948)	· =	Summary (PTO-413) Paper No(s) Informal Patent Application (PTO-		

U.S. Patent and Trademark Office PTO-326 (Rev. 04-01)

3) Information Disclosure Statement(s) (PTO-1449) Paper No(s)

6) Other:

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DETAILED ACTION

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-5 and 14-21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Su el al. (US 6,133,096) in view of Cho et al. (US 6,027,971).

Regarding claims 1, 2, 4, 14, 15, 19, Su et al. discloses a semiconductor memory device comprising: a silicon substrate (1) (Su el al.'s col.3, lines38-40) including a peripheral memory region (90) and a core memory region (70); a transistor formed on the peripheral memory region; one set of dual gate core memory structures (15) formed in the core memory region, the dual gate core memory structures (15) including a stacked layer arrangement of semiconductor layers (7, 10) and a dielectric material layer (9), the dual gate core memory structure having sidewall portions; sidewall spacer structures (21) of silicon nitride (Su el al.'s col.6 lines 13-18) formed on the sidewall portions of dual gate core memory structures. See Su el al. Fig.7B and Fig.15.

Su et al. does not explicitly teach that the silicon nitride for forming spacer structures (21) have the chemical formula of Si3N4.

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Cho et al. discloses a semiconductor memory device comprising: a dual gate core memory structure (62) formed in the core memory region; a sidewall spacer structures (68) formed on sidewall portions of the dual gate core memory structures, wherein the sidewall spacer structure formed of silicon nitride (Si3N4). Cho's Fig.8A and col.5 lines 63-67.

It is known in the art and also taught by Cho that silicon nitride is usually preferred to Si3N4 in semiconductor device. Therefore, it would have been obvious to one of ordinary skill in the art to form sidewall spacer structures of silicon nitride (Si3N4) as taught by Cho et al.

It is noted that, claimed structure and structure formed by the combination of Su and Cho are identical, such that both structure include sidewall spacer structures formed from silicon nitride (Si3N4, an anti-reflective coating material). Therefore, it is inherent that, the sidewall spacer structures in above combined device is also capable to protect the stacked layer arrangement during etching operations and is compatible with ion implantation and salicidation fabrication process as claimed device.

When the structure recited in claims reference is substantially identical in structure or composition, or are produced by identical or substantially identical to that of the claims, claimed properties of functions are presumed to be inherent. In re Best,195 USPQ 430, 433 (CCPA 1977). 1990).

The expressions "dual-purpose" and "being used for lithographic patterning for protecting said stacked layer arrangement during etching operations" In claims 1, 4, 14,

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17, 19 and 21 are considered as intended use limitations and are not considered towards patentability. A recitation of the intended use of the claimed invention must result in a structural difference between the claimed invention and the prior art in order to patentability distinguish the claimed invention from the prior art. If the prior art structure is capable of performing the intended use, then it meets the claim. In a claim drawn to a process of making, the intended use must result in a manipulative difference as compared to the prior art. See *In re Casey*, 152 USPQ 235 (CCPA 1967) and *In re Otto*, 136 USPQ 458, 459 (CCPA 1963).

Regarding claims 3, 5, 16, 17, 18, Su el al. teaches that the silicon nitride spacer structures (21) being deposited in a thickness of 1000 angstroms. Su et al.'s col.6, lines 13-18.

Regarding claims 20 and 21, as shown in Su et al. 's Fig.15, the silicon nitride spacer also being a pattern formation structure for at least one peripheral memory element.

Response to Amendment

2. Applicant's arguments with respect to claims 1-8 and 12-24 have been considered but are not persuasive.

Applicants argue that none of the applied arts teaches that the spacer structure serves a dual purpose as claimed. In response, as discussed in previous action and above, the limitation "dual-pyrpose" is considered as an intended used limitation which is not considered towards patentability. A recitation of the intended use of the claimed invention must result in a structural difference between the claimed invention and the

prior art in order to patentability distinguish the claimed invention from the prior art. If the prior art structure is capable of performing the intended use, then it meets the claim. In a claim drawn to a process of making, the intended use must result in a manipulative difference as compared to the prior art. See *In re Casey*, 152 USPQ 235 (CCPA 1967) and *In re Otto*, 136 USPQ 458, 459 (CCPA 1963).

Conclusion

- 3. THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a). A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.
- 4. Papers related to this application may be submitted to Technology center (TC) 2800 by facsimile transmission. Papers should be faxed to TC 2800 via the TC 2800 Fax center located in Crystal Plaza 4, room 4-C23. The faxing of such papers must conform with the notice published in the Official Gazette, 1096 OG 30 (November 15, 1989). The Group 2811 Fax Center number is (703) 308-7722 and 308-7724. The

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Group 2811 Fax Center is to be used only for papers related to Group 2811 applications.

- 5. Any inquiry concerning this communication or any earlier communication from the Examiner should be directed to CUONG Q NGUYEN whose telephone number is (703) 308-1293. The Examiner is in the Office generally between the hours of 6:30 AM to 5:00 PM (Eastern Standard Time) Monday through Thursday.
- 6. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor TOM THOMAS who can be reached on (703) 308-2772. The fax phone number for the organization where this application or proceeding is assigned is (703) 308-7722 or 308-7724.
- 7. Any inquiry of a general nature or relating to the status of this application should be directed to the Technology Center Receptionists whose telephone number is 308-0956.

Cuong Nguyen

9/27/02